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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Nobuyuki MISE et al.

Serial No.: 10/090,761

Filed: March 6, 2002

For: **ETCHING METHOD OF HARDLY-ETCHED MATERIAL AND
SEMICONDUCTOR FABRICATING METHOD AND
APPARATUS USING THE METHOD**

Group: 1765

Examiner: Lan Vinh

AMENDMENTMail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

June 24, 2004

Sir:

In response to the Office Action (Paper No. 031804) dated on March 24, 2004, please amend the above-identified application as follows.

Amendments to the Claims begin on page 2 of this paper.

Remarks/Arguments begin on page 11 of this paper.